



Development and Applications of Microwave/Millimeter Wave Diagnostics in Industry, 2nd Edition

Guest Editors:

Prof. Dr. Atsushi Mase

Global Innovation Center, Kyushu University, Kasuga 816-8580, Japan

Prof. Dr. Neville C. Luhmann

1. Department of Electrical and Computer Engineering, University of California, Davis, CA 95616, USA
2. Co-Director of Davis MM Wave Research Center, University of California, Davis, CA 95616, USA

Deadline for manuscript submissions:

30 September 2024

Message from the Guest Editors

The ever accelerating progress in microwave- and millimeter-wave devices and circuits, such as monolithic microwave integrated circuits (MMICs), and data processing including computer technology has contributed to the rapid advancement in diagnostic technology. This includes micro- to millimeter-wave imaging including optics imaging, synthetic imaging, and MIMO (multi-input multi-output) imaging. They have become of critical importance in various applications due to the possibility of high localization and accessibility of the measurements.

In this Special Issue, the scientific papers related to industrial applications of micro- to millimeter-wave diagnostics will be accepted, which include system development, data processing techniques, system application results, and physics understandings of the results. The potential applications may include the above-mentioned measurements. However, many valuable studies can be accepted for future advancements in this field.





an Open Access Journal by MDPI

Editor-in-Chief

Prof. Dr. Giulio Nicola Cerullo
Dipartimento di Fisica,
Politecnico di Milano, Piazza L.
da Vinci 32, 20133 Milano, Italy

Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), Inspec, CAPlus / SciFinder, and other databases.

Journal Rank: JCR - Q1 (Engineering, Multidisciplinary) / CiteScore - Q1 (General Engineering)

Contact Us

Applied Sciences Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/applsci
applsci@mdpi.com
[X@Applsci](#)